

Application Data Sheet

Application Information

Application number::

Filing Date::

Application Type::

Regular

Subject Matter::

Utility

Title ::

LASER IRRADIATION
APPARATUS, LASER
IRRADIATION METHOD,
AND METHOD FOR
MANUFACTURING A
SEMICONDUCTOR DEVICE

Attorney Docket Number:: 0756-7263

Total Drawing Sheets:: 16

Small Entity?:: No

Applicant Information

Applicant Authority Type:: Inventor

Primary Citizenship Country:: Japan

Given Name:: Shunpei

Middle Name::

Family Name:: YAMAZAKI

Name Suffix::

City of Residence:: Setagaya

State or Province of Residence:: Tokyo

Country of Residence:: Japan

Street of mailing address:: c/o Semiconductor Energy
Laboratory Co., Ltd.
398, Hase
Atsugi-shi
Kanagawa-ken
Japan
243-0036

Applicant Authority Type:: Inventor
Primary Citizenship Country:: Japan
Given Name:: Koichiro
Middle Name::
Family Name:: TANAKA
Name Suffix::
City of Residence:: Atsugi-shi
State or Province of Residence:: Kanagawa-ken
Country of Residence:: Japan
Street of mailing address:: c/o Semiconductor Energy
Laboratory Co., Ltd.
398, Hase
Atsugi-shi
Kanagawa-ken
Japan
243-0036

Correspondence Information

Correspondence Customer Number :: 31780
E-Mail address:: erobinson@ripl.com

Representative Information

Representative Customer Number:: 31780

Domestic Priority Information

Application ::	Continuity Type::	Parent Application::	Parent Filing Date::

Foreign Priority Information

Country::	Application number::	Filing Date::	Priority Claimed::
Japan	2003-071608	03/17/2003	Yes

Assignee Information

Assignee name:: Semiconductor Energy
Laboratory Co., Ltd.
Street of mailing address:: 398 Hase
City of mailing address:: Atsugi-shi
State or Province of mailing address:: Kanagawa-ken
Country of mailing address:: Japan
Postal or Zip Code of mailing address:: 243-0036